

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Confirmation No.: 8995

Makiko KITAZOE et al.

Group Art Unit: 1792

Application No.: 10/593,444

Examiner: Joseph Albert MILLER, Jr.

Filed: February 5, 2007

Attorney Docket No.: 029567-00011

For: UNIT-LAYER POST-PROCESSING CATALYST CHEMICAL-VAPOR
DEPOSITION APPARATUS AND ITS FILM FORMING METHOD

RESPONSE WITH A REQUEST FOR CONTINUED EXAMINATION

Mail Stop AFTER FINAL

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

January 11, 2010

Sir:

In reply to the outstanding Office Action dated September 15, 2009, please amend the application as shown on the following pages. The period for response is extended by one month, from December 15, 2009 to January 15, 2010, and the payment of the appropriate fee is submitted herewith via EFS. A Request for Continued Examination and the required fee are also submitted herewith.

Amendments to the Claims begin on page 2.

Remarks begin on page 8.

Conclusion begins on page 12.